

Electronic Devices

Lecture 8

23-08-2018

Density of states function

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Table 3.1 | Effective density of states function and effective mass values

	$N_c \text{ (cm}^{-3}\text{)}$	$N_v \text{ (cm}^{-3}\text{)}$	m_n^*/m_0	m_p^*/m_0
Silicon	2.8×10^{19}	1.04×10^{19}	1.08	0.56
Gallium arsenide	4.7×10^{17}	7.0×10^{18}	0.067	0.48
Germanium	1.04×10^{19}	6.0×10^{18}	0.55	0.37

$$N_c = 2 \left(\frac{2\pi m_n^* kT}{h^2} \right)^{3/2}$$

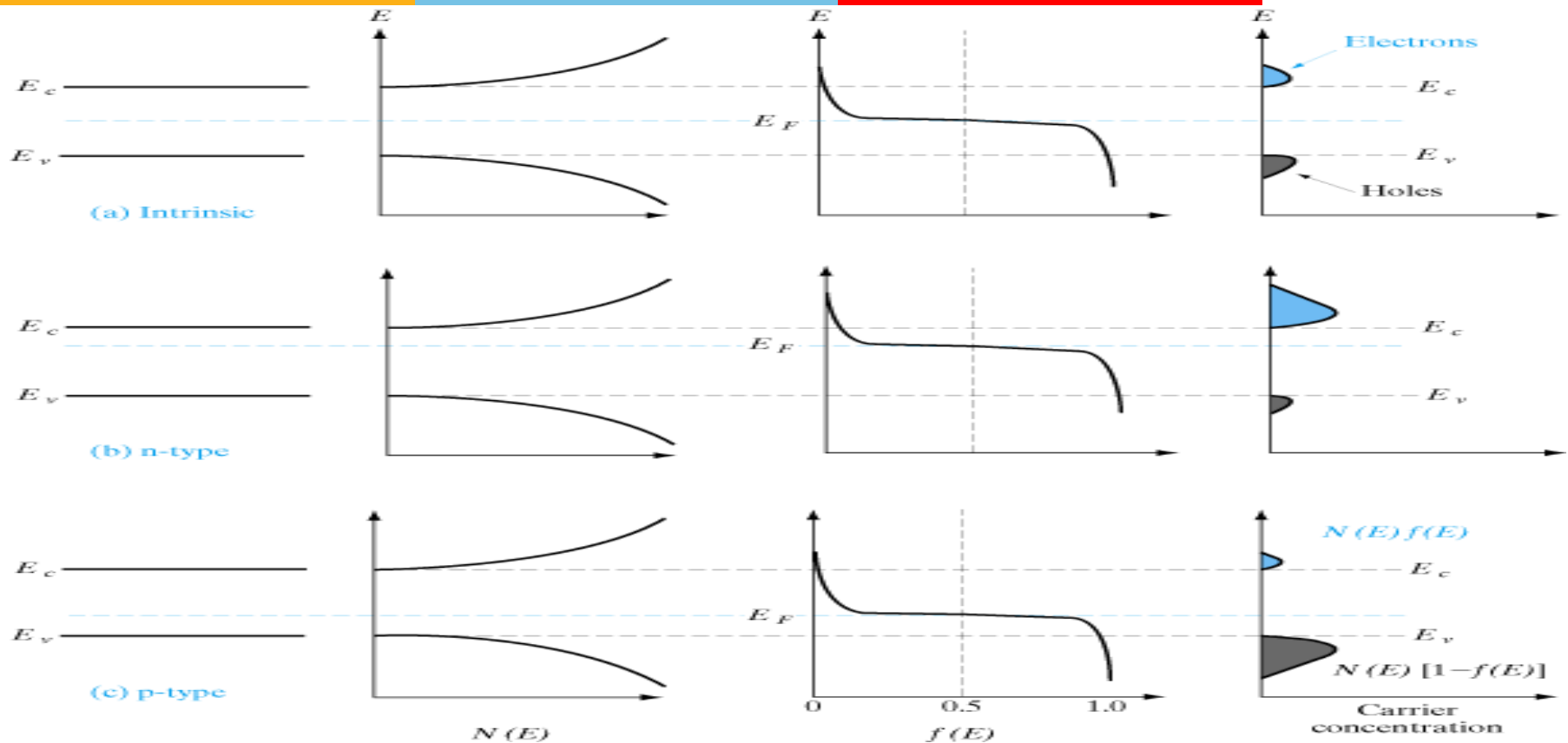
$$N_v = 2 \left(\frac{2\pi m_p^* kT}{h^2} \right)^{3/2}$$

Schematic Band Diagram

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Schematic band diagram, density of states, Fermi-Dirac distribution, and the carrier concentrations for (a) intrinsic, (b) n-type, and (c) p-type semiconductors at thermal equilibrium.

- Recall these two equations :

$$n_0 = N_C f(E_C) = N_C e^{-(E_C - E_F)/kT}$$

$$p_0 = N_V [1 - f(E_V)] = N_V e^{-(E_F - E_V)/kT}$$

Intrinsic electron and hole concentrations where almost $E_F = E_i$:

$$p_i = N_V e^{-(E_i - E_V)/kT} \quad n_i = N_C e^{-(E_C - E_i)/kT}$$

$$n_0 p_0 = (N_C e^{-(E_C - E_F)/kT}) (N_V e^{-(E_F - E_V)/kT}) =$$

$$N_C N_V e^{-(E_C - E_V)/kT} = N_C N_V e^{-E_g/kT}$$

$$n_i p_i = (N_C e^{-(E_C - E_i)/kT}) (N_V e^{-(E_i - E_V)/kT}) =$$

$$N_C N_V e^{-(E_C - E_V)/kT} = N_C N_V e^{-E_g/kT}$$

Thus, intrinsic electron and hole concentrations are equal
are created in pairs : $n_i = p_i$:

Thus, intrinsic concentration :

Also,

Note: n_i of Si at RT = $1.5 \times 10^{10} \text{ cm}^{-3}$ & $E_C - E_i = E_g/2$ if $N_C = N_V$

$$n_0 p_0 = n_i^2$$

$$n_i = \sqrt{N_C N_V} e^{-E_g / 2kT}$$

Two convenient expressions :

$$n_0 = N_C e^{-(E_C - E_F)/kT} = N_C e^{-(E_C - E_i)/kT} e^{(E_F - E_i)/kT} = n_i e^{(E_F - E_i)/kT}$$

Thus,

$$p_0 = N_V e^{-(E_F - E_V)/kT} = N_V e^{-(E_i - E_V)/kT} e^{(E_i - E_F)/kT} = n_i e^{(E_i - E_F)/kT}$$

$$n_0 = n_i e^{(E_F - E_i)/kT}$$

$$p_0 = n_i e^{(E_i - E_F)/kT}$$

Find the equilibrium electron and hole concentrations and the location of the Fermi level (with respect to the intrinsic Fermi level E_i) in silicon at 300K if the silicon contains $8 \times 10^{16} \text{ cm}^{-3}$ Arsenic (As) and $2 \times 10^{16} \text{ cm}^{-3}$ boron (B) atoms.

$$n = 6 \times 10^{16} \text{ cm}^{-3}$$

$$p = \frac{n_i^2}{n} = 3.5 \times 10^3 \text{ cm}^{-3}$$

$$E_f - E_i = kT \ln(n / n_i) = 0.393 eV$$

$$\begin{aligned} E_c - E_f &= kT \ln(N_c / n) = 0.0258 \ln(2.8 \times 10^{19} / 6 \times 10_{16}) \\ &= 0.159 eV \end{aligned}$$

$$n_0 = n_i e^{(E_F - E_i) / kT}$$

$$p_0 = n_i e^{(E_i - E_F) / kT}$$

$$n_i = \sqrt{N_C N_V} e^{-E_g / 2kT}$$

$$N_C = 2 \left(\frac{2\pi m_n^* kT}{h^2} \right)^{3/2}$$

$$N_V = 2 \left(\frac{2\pi m_p^* kT}{h^2} \right)^{3/2}$$

$$n_i(T) = 2 \left(\frac{2\pi kT}{h^2} \right)^{3/2} (m_n^* m_p^*)^{3/4} e^{-E_g / 2kT}$$

Take n_i to calculate n_0 and p_0 in the following equations:

$$n_0 = n_i e^{(E_F - E_i) / kT}$$

$$p_0 = n_i e^{(E_i - E_F) / kT}$$

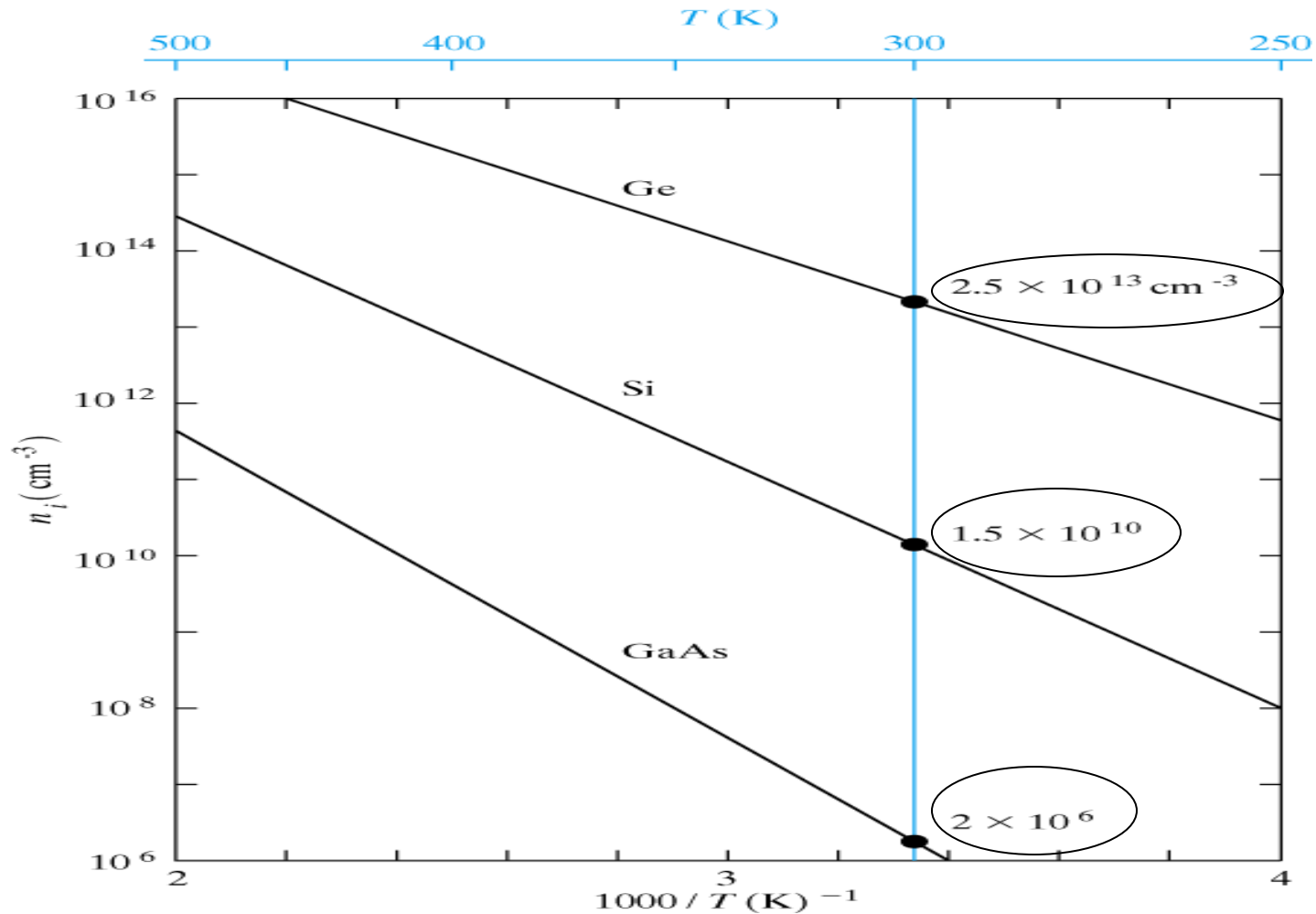


Figure 3—17

Intrinsic carrier concentration for Ge, Si, and GaAs as a function of inverse temperature. The room temperature values are marked for reference.

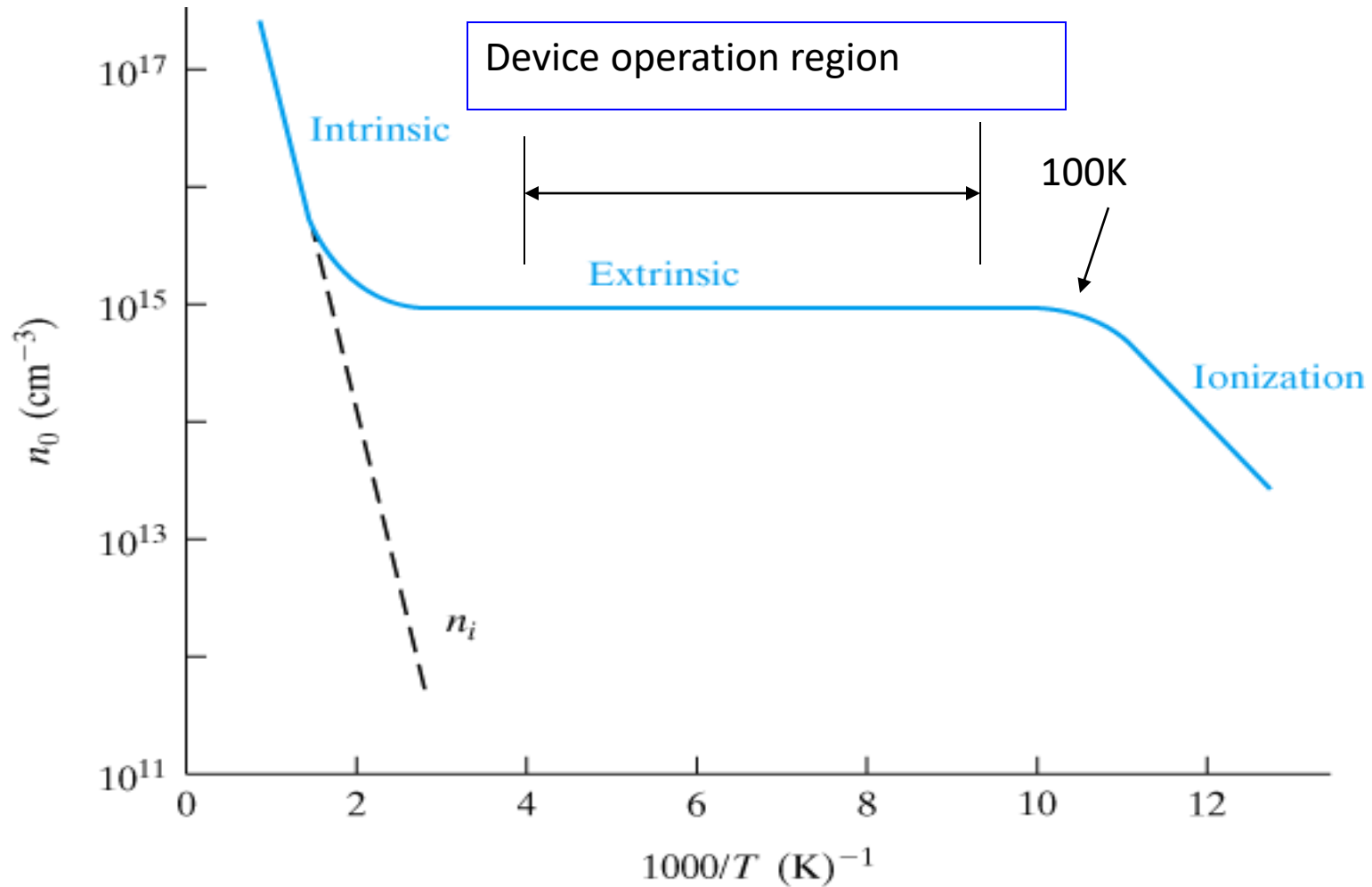


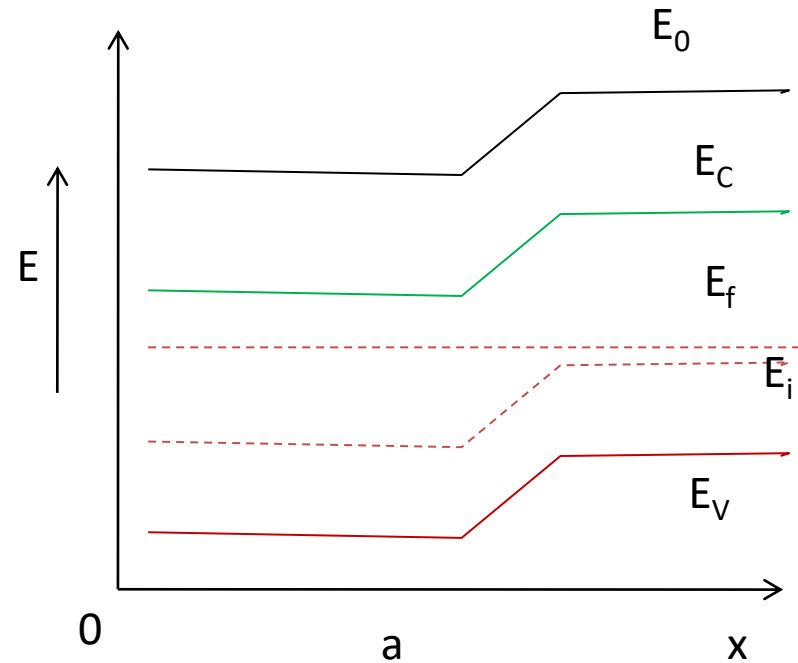
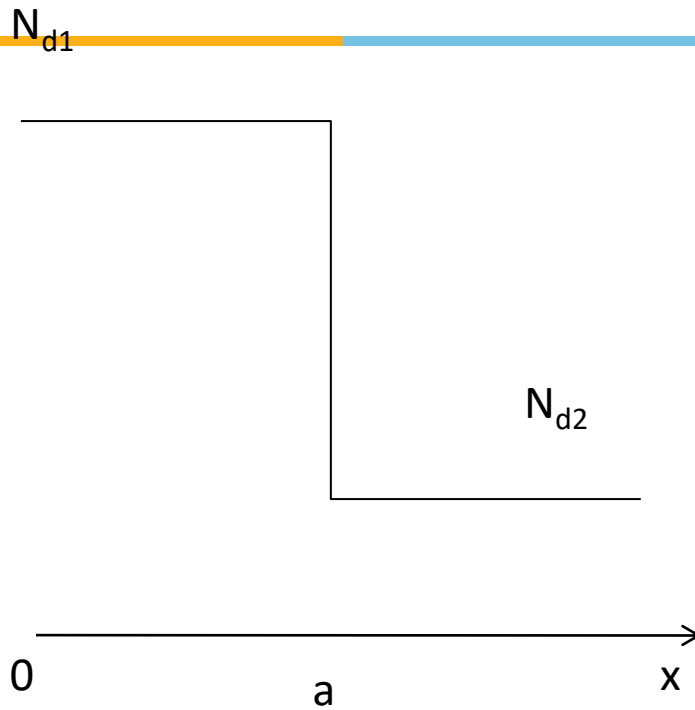
Figure 3—18

Carrier concentration vs. inverse temperature for Si doped with 10^{15} donors/cm³.

A silicon crystal is known to contain 10^{-4} atomic percent of arsenic (As) as an impurity. It then receives a uniform doping $3 \times 10^{16} \text{ cm}^{-3}$ phosphorous (P) atoms and a subsequent uniform doping of 10^{18} cm^{-3} boron (B) atoms. A thermal annealing treatment then completely activates all impurities.

- (a) What is the conductivity type of this silicon sample?
- (b) What is the density of the majority carriers?

Inhomogeneously Doped Semiconductor



Electronic Devices

Lecture 9

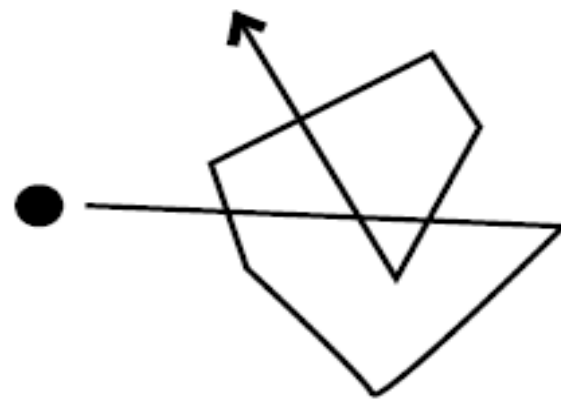
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Thermal Motion



In thermal equilibrium, carriers are not sitting still:

- undergo collisions with vibrating Si atoms (*Brownian motion*)
- electrostatically interact with charged dopants and with each other



Characteristic time constant of thermal motion - mean free time between collisions:

$$\tau_c \equiv \text{collision time [s]}$$

In between collisions, carriers acquire high velocity:

$$v_{th} \equiv \text{thermal velocity [cm/s]}$$

Characteristic length of thermal motion:



$$\lambda \equiv \text{mean free path [cm]}$$

$$\lambda = v_{th} \tau_c$$

Put numbers for Si at 300 K:

$$\tau_c \simeq 10^{-14} \sim 10^{-13} \text{ s}$$

$$v_{th} \simeq 10^7 \text{ cm/s}$$

$$\Rightarrow \lambda \simeq 1 \sim 10 \text{ nm}$$

For reference, state-of-the-art MOSFETs today:

$$L_g \simeq 50 \text{ nm}$$

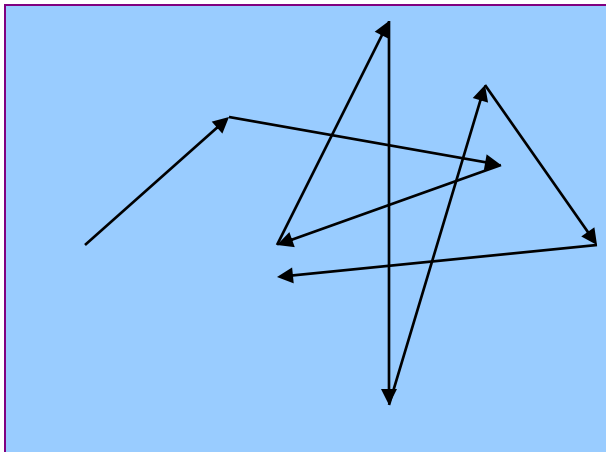
\Rightarrow carriers undergo many collisions in modern devices

CONDUCTIVITY AND MOBILITY



To calculate current flow in presence of electric and magnetic field we have to take into account the collisions of the charge carriers with the lattice and impurities.

Ease with which electrons and holes can flow through the crystal determines their mobility within the solid.



$$\begin{array}{c} \mathcal{E}_x \\ \text{Field} \\ \mathbf{v}_x = -\mu_n \mathcal{E}_x \end{array}$$

Net force experienced by each electron $-q\mathcal{E}_x$

$$-nqE_x = \left. \frac{dp_x}{dt} \right|_{field}$$

Let $N(t)$ is the number of electrons that have not undergone collision by time t .

The rate of decrease in $N(t)$ at any time t is

$$-\frac{dN(t)}{dt} = \frac{1}{\tau} N(t)$$

$$N(t) = N_o e^{-t/\tau}$$

The probability that any electron has a collision in time dt is $\frac{dt}{\tau}$

The differential change in p_x due to collisions is

$$dp_x = -p_x \frac{dt}{\tau}$$

$$\left. \frac{dp_x}{dt} \right|_{\text{collision}} = -\frac{p_x}{\tau}$$

$$-\frac{p_x}{\tau} - nq\mathcal{E}_x = 0$$

$$\langle p_x \rangle = \frac{p_x}{n} = -q\tau \mathcal{E}_x$$

$$\langle v_x \rangle = \frac{\langle p_x \rangle}{m_n^*} = -\frac{q\tau}{m_n^*} \mathcal{E}_x$$

-The average acceleration and deceleration must be zero for steady state

-Average momentum

-Average velocity

m_n^* - conductivity effective mass for electrons

CONDUCTIVITY AND MOBILITY



for electrons: $v_{dn} = -\mu_n E$ for holes: $v_{dp} = \mu_p E$

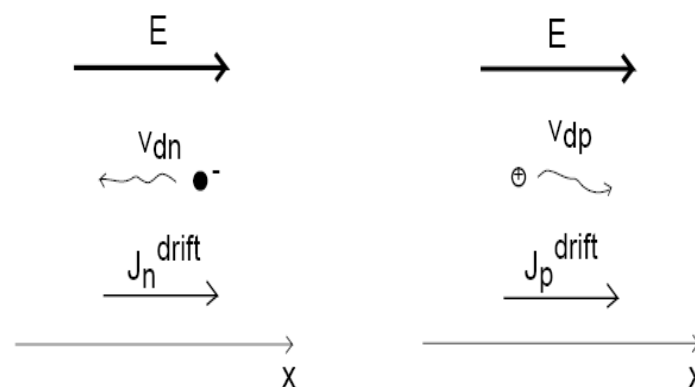
Drift current

Net velocity of charged particles \Rightarrow electric current:

Drift current density \propto *carrier drift velocity*
 \propto *carrier concentration*
 \propto *carrier charge*

$$J_n^{drift} = -qn v_{dn} = qn \mu_n E$$

$$J_p^{drift} = qp v_{dp} = qp \mu_p E$$



Total drift current:

$$J^{drift} = J_n^{drift} + J_p^{drift} = q(n\mu_n + p\mu_p)E$$

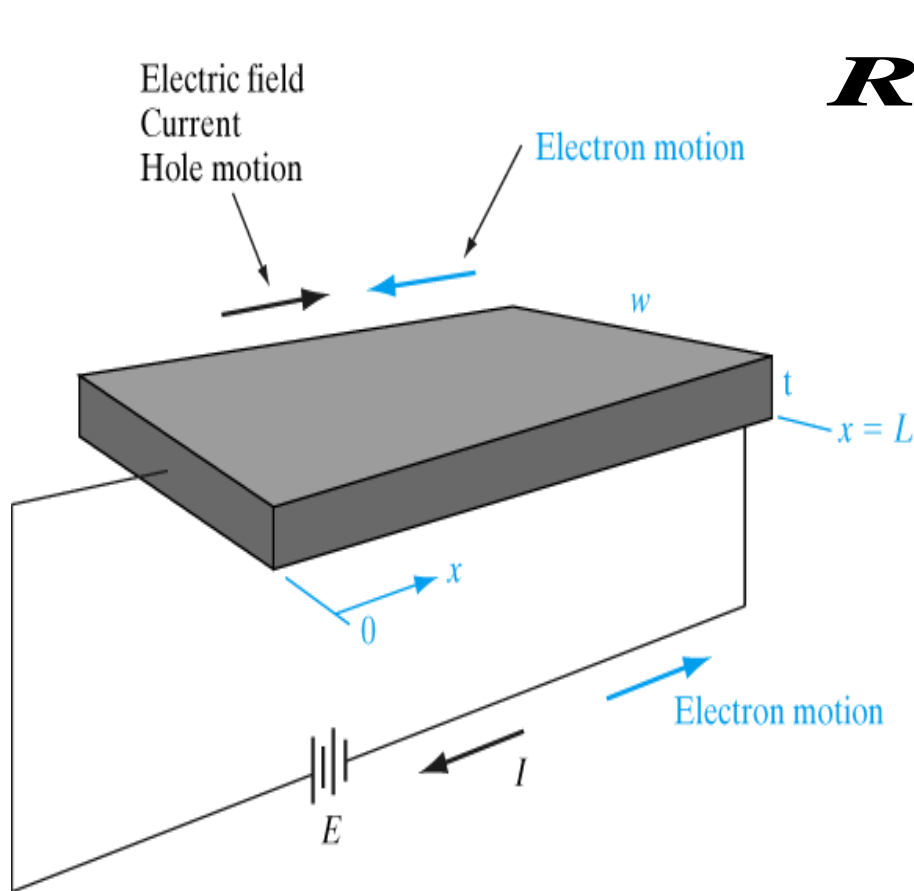
Has the shape of *Ohm's Law*: $J = \sigma E = \frac{E}{\rho}$

$$\sigma \equiv \text{conductivity} [\Omega^{-1} \cdot \text{cm}^{-1}]$$

$$\rho \equiv \text{resistivity} [\Omega \cdot \text{cm}]$$

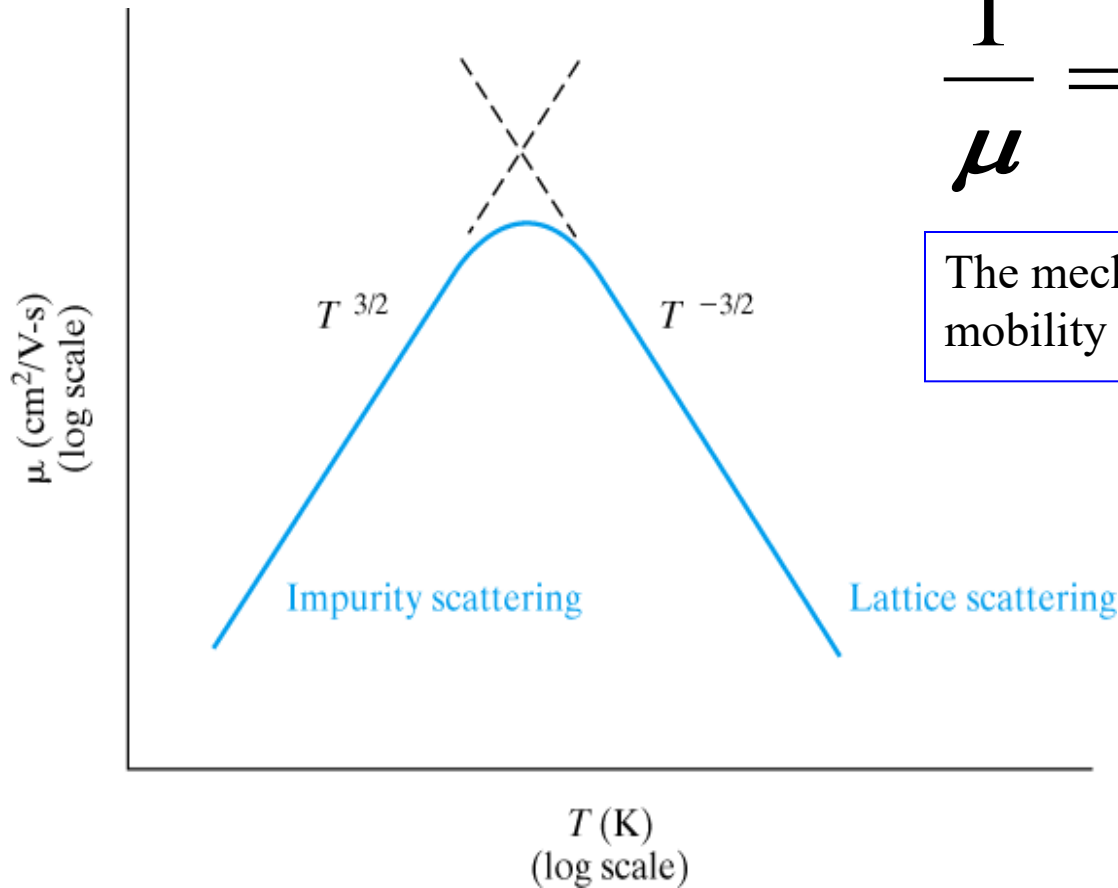
$$\rho = \frac{1}{\sigma} = \frac{1}{q(n\mu_n + p\mu_p)}$$

Drift of electrons and holes in a semiconductor bar



$$R = \frac{\rho L}{wt} = \frac{L}{wt} \frac{1}{\sigma}$$

Impurity & Lattice Scatterings



$$\frac{1}{\mu} = \frac{1}{\mu_I} + \frac{1}{\mu_l}$$

The mechanism causing the lower mobility value dominates !

Figure 3—21

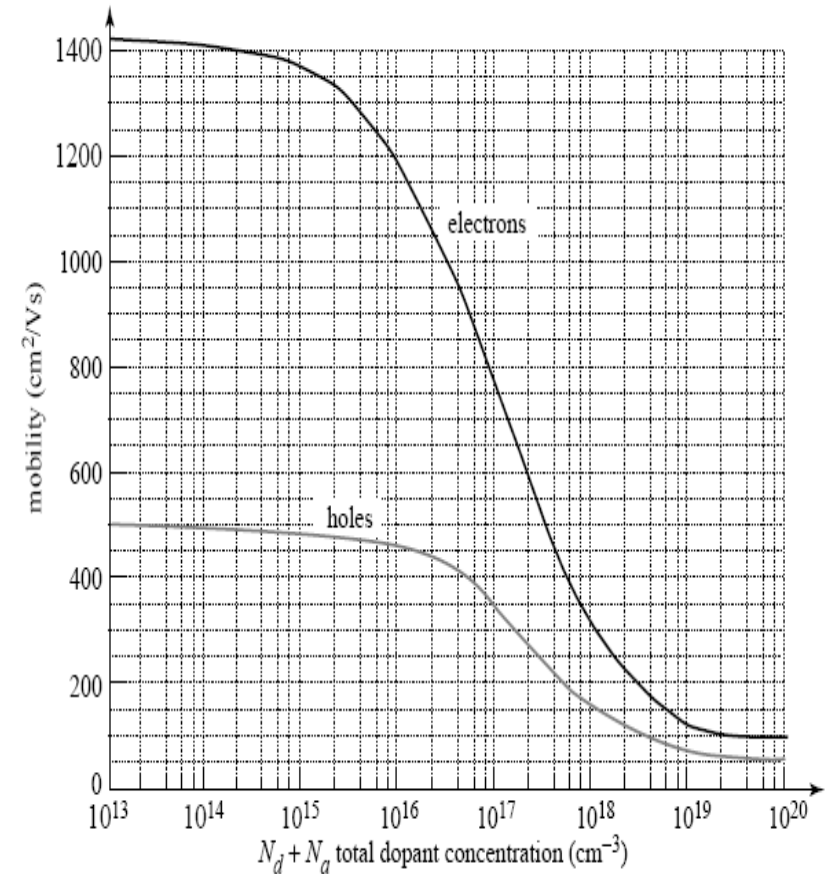
Approximate temperature dependence of mobility with both lattice and impurity scattering.

Effect of temperature and doping on mobility



$\mu \propto T^{-3/2}$ lattice scattering

$\mu \propto T^{3/2}$ impurity scattering



Mobility depends on doping. For Si at 300K:

Mobility vs. doped impurity concentration

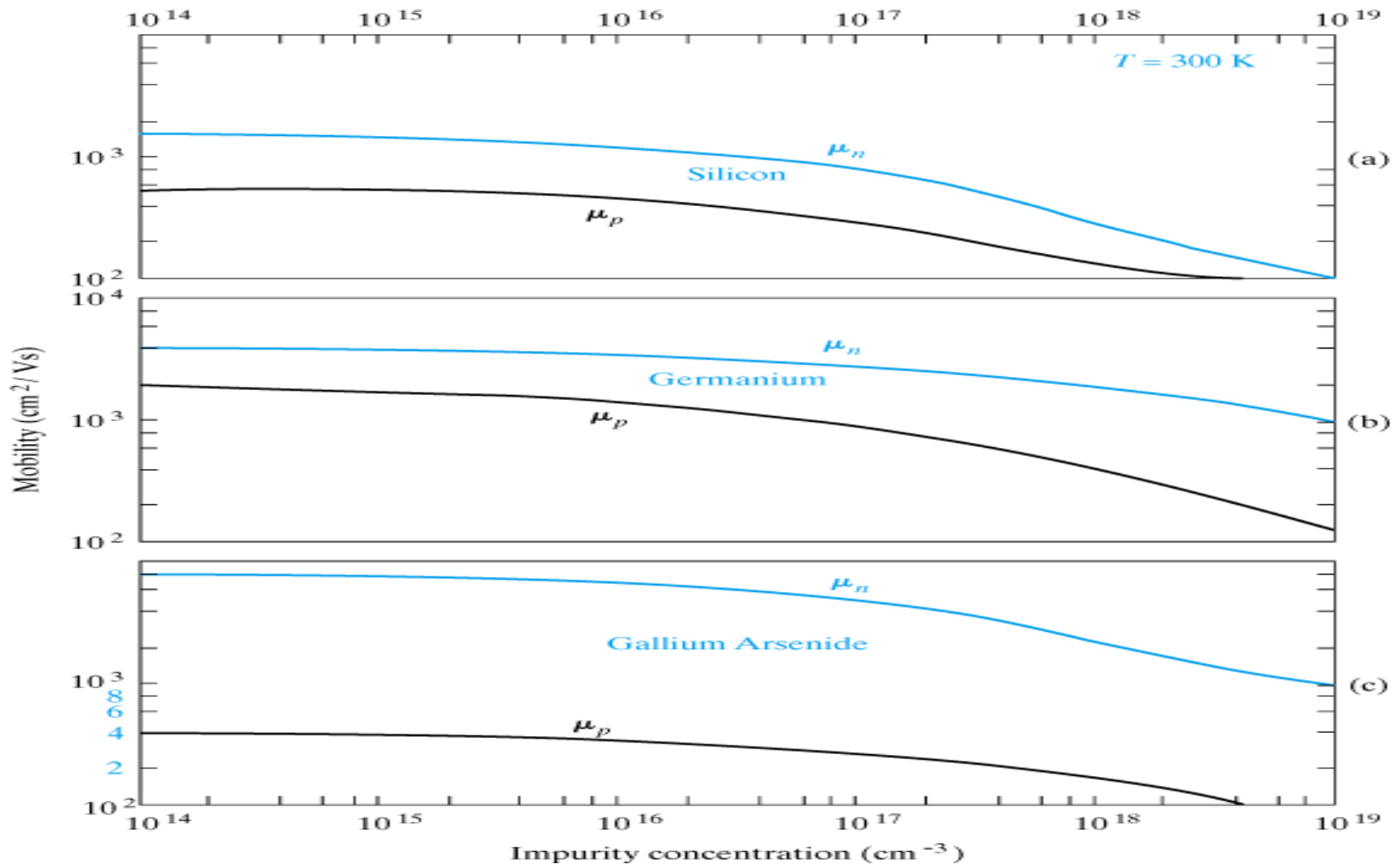


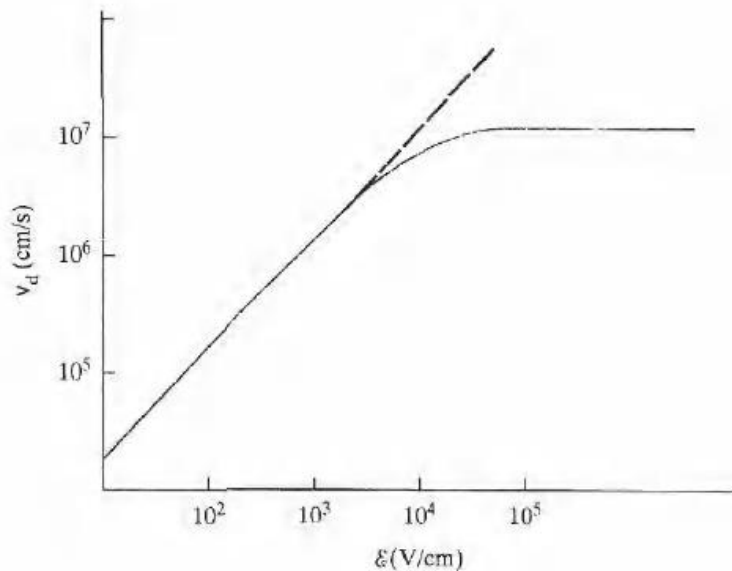
Figure 3—23

Variation of mobility with total doping impurity concentration ($N_a + N_d$) for Ge, Si, GaAs at 300 K.

Saturation of electron drift velocity at high electric field



Velocity reaches a saturation value of the mean thermal velocity.



Field required to saturate velocity:

$$\mathcal{E}_{sat} = \frac{v_{sat}}{\mu}$$

Since μ depends on doping, \mathcal{E}_{sat} depends on doping too.

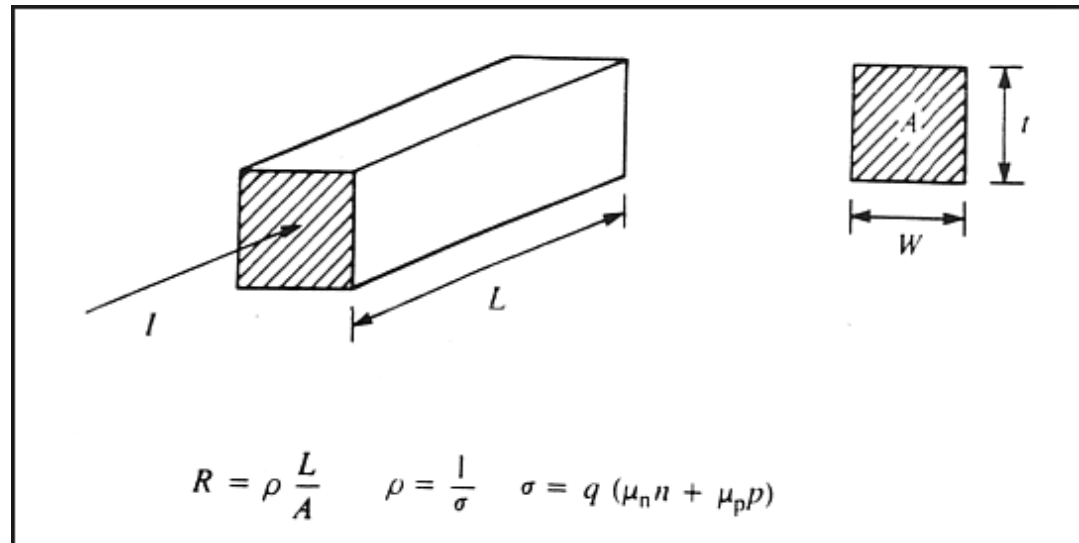
Electrical conductivity

- $\sigma_i = en_i(\mu_n + \mu_p)$ is the intrinsic conductivity of a semiconductor material
- For extrinsic semiconductors assuming complete ionization, N_d or $N_a \gg n_i$
Hence the conductivity reduces to
$$\sigma_n \approx eN_d\mu_n \text{ and } \sigma_p \approx eN_a\mu_p$$

thus the conductivity is purely dependent on the majority carrier concentration

Electrical resistance

- $J = \sigma E = \sigma \frac{V}{L}$ where L is the length of the SC material
- $I = JA = \frac{\sigma VA}{L}$ and the electrical resistance is given by
- $R = \frac{V}{I} = \frac{1}{\sigma} \frac{L}{A} = \frac{\rho L}{A}$



Electrical resistivity

- $\rho = \frac{1}{\sigma} = \frac{1}{e(n\mu_n + p\mu_p)}$ is the electrical resistivity
- Resistance, conductance, resistivity and conductivity, depend only on the majority carrier concentration and not on the minority carrier concentration